Low Temperature Dissipation in Ultra-thin Cantilevers

- Temperature dependent studies of the mechanical quality factor (Q) of ultra-sensitive single-crystal silicon cantilevers used for measuring small forces.
- Reduced Q observed at ~135K due to thermal oxide on the surface.
- Cantilevers fabricated that can be annealed \textit{in situ} in order to remove surface oxide and enhance Q, thereby enhancing sensitivity of the cantilever.

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